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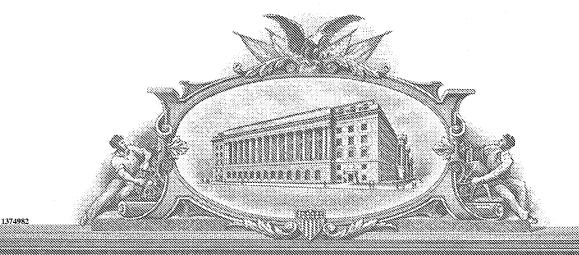
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UNITED STATES DEPARTMENT OF COMMERCE

United States Patent and Trademark Office

September 30, 2005

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APPLICATION NUMBER: 60/603,843

FILING DATE: August 23, 2004

RELATED PCT APPLICATION NUMBER: PCT/US05/29815

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PROVISIONAL APPLICATION FOR PATENT COVER SHEET

•	This is a request for filing	<u>a PROVISIONAL APPLICATION FOR PATENT under 37 CFR 1.53(c).</u>
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	INVENTOR(S)							
Given Name (first and middle [if any])	Family Name or Surname			Residence (City and either State or Foreign Country)				
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Thomas R.	1_			Lisle, IL			₽₩	
Dean	Richardson			Wilmette, IL			38.5	
Additional inventors are being name	,		mbered sheets	attached hereto			00	
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SYSTEM AND METHOD OF SILICON WAVEGUIDES ANI			COUPLING	3 EFFICIE	NCY E	BETWEEN		
Direct all correspondence to:	CORRESP	ONDENCE A	DDRESS					
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EN	CLOSED APPLICA	ATION PART	S (check all tha	at apply)				
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Application Data Sheet. See 37 CFR	1.76	L	Other (spec	L				
METHOD OF PAYMENT OF FILING FEE	FOR THIS PRO	VISIONAL AP	PLICATION FO	R PATENT				
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fees or credit any overpayment to	The Commissioner is hereby authorized to charge filing fees or credit any overpayment to Deposit Account Number: 50-1873 \$160.00							
Payment by credit card. Form PTO-2038 is attached. The invention was made by an agency of the United States Government or under a contract with an agency of the								
United States Government.								
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Yes, the name of the U.S. Government agency and the Government contract number are:								
Respectfully submitted, Date 08/23/2004								
REGISTRATION NO. 43,322							2	
YPED or PRINTED NAME Romi N. Bose (if appropriate) 630/527 4410 A5-013PRO						OV-US		
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This collection of information is required by 37 CFR 1.51. The information is used by the public to file (and by the PTO to process) a provisional application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 8 hours to complete, including gathering, preparing, and submitting the complete provisional application to the PTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, Washington, D.C. 20231. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Box Provisional Application, Assistant Commissioner for Patents, Washington, D.C. 20231.

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FEE TRANSMITTAL for FY 2004

Effective 10/01/2003. Patent fees are subject to annual revision.

Applicant claims small entity status. See 37 CFR 1.27

TOTAL AMOUNT OF PAYMENT

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Complete if Known						
Application Number						
Filing Date						
First Named Inventor	A.N.M. Masum Choudhury					
Examiner Name	Unknown					
Art Unit	Unknown					
Attorney Docket No.	A5-013 PROV US					

Date

METHOD OF PAYMENT (check all that apply)	FEE CALCULATION (continued)					
Check Credit card Money Other None	3. ADDITIONAL FEES					
Deposit Account:	Large Entity Small Entity					
Deposit FO 4070	Fee I Code	Fee (\$)	Fee Code	Fee (\$)	Fee Description	Fee Paid
Account 50-1873 Number	1051	130	2051	65	Surcharge - late filing fee or oath	
Deposit Account Molex Incorporated	1052	50	2052	25	Surcharge - late provisional filing fee or cover sheet	
Name The Director is authorized to: (check all that apply)	1053	130	1053	130	Non-English specification	
Charge fee(s) indicated below Credit any overpayments	1812 2	,520	1812 2	2,520	For filing a request for ex parte reexamination	
Charge any additional fee(s) or any underpayment of fee(s)	1804	920*	1804	920*	Requesting publication of SIR prior to Examiner action	·
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FEE CALCULATION	1251	110	2251	55	Extension for reply within first month	
1. BASIC FILING FEE	1252	420	2252	210	Extension for reply within second month	ļ
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1001 770 2001 385 Utility filing fee	1255 2	,010	2255	1,005	Extension for reply within fifth month	
1002 340 2002 170 Design filing fee	1401	330	2401	165	Notice of Appeal	
1003 530 2003 265 Plant filing fee	1402	330	2402	165	Filing a brief in support of an appeal	
1004 770 2004 385 Reissue filing fee	1403	290	2403	145	Request for oral hearing	
1005 160 2005 80 Provisional filing fee 160	1451 1	,510	1451	1,510	Petition to institute a public use proceeding	
SUBTOTAL (1) (\$) 160	1452	110	2452	55	Petition to revive - unavoidable	
2. EXTRA CLAIM FEES FOR UTILITY AND REISSUE	1453 1	,330	2453	665	Petition to revive - unintentional	
Fee from	1501 1	,330	2501	6 65	Utility issue fee (or reissue)	
Total Claims 3 -20** = 0 x 9 = 0	1502	480	2502		Design issue fee	
Independent 1 3** 0 V 13 10	1503	640	2503		Plant issue fee	
Claims -3 - 0 - 140 - 10 - 10 - 10 - 10 - 10	1460	130	1460	130	Petitions to the Commissioner	
	1807	50	1807	7 50	Processing fee under 37 CFR 1.17(q)	
Large Entity Small Entity Fee Fee	1806	180	1806		Submission of Information Disclosure Stmt	
Code (\$) Code (\$)	8021	40	8021	40	Recording each patent assignment per property (times number of properties)	
1202 18 2202 9 Claims in excess of 20 1201 86 2201 43 Independent claims in excess of 3	1809	770	2809	385	Filing a submission after final rejection (37 CFR 1.129(a))	
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1204 86 2204 43 ** Reissue independent claims					examined (37 CFR 1.129(b))	
over original patent	1801	770	2801		Request for Continued Examination (RCE)	
1205 18 2205 9 ** Reissue claims in excess of 20 and over original patent	1802	900	1802	900	Request for expedited examination of a design application	
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SUBMITTED BY					(Complete (if applicable))	
Name (Print/Type) Romi Na Bose		gistra	tion No.	43	322 Telephone 630-527-4419	

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PROVISIONAL APPLICATION COVER SHEET Additional Page

PTO/SB/16 (02-01)
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A5-013PROV-US Docket Number INVENTOR(S)/APPLICANT(S) Residence Given Name (first and middle [if any]) Family or Surname (City and either State or Foreign Country) Ariela ISRAEL Donval Ram Oron **ISRAEL** ISRAEL Moshe Oron

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SYSTEM AND METHOD OF IMPROVING LIGHT COUPLING EFFICIENCY BETWEEN SILICON WAVEGUIDES AND OPTICAL FIBERS

BACKGROUND OF THE INVENTION

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1. Field of the Invention

The present invention relates generally to planar lightwave circuits and, more particularly, to efficiently coupling light from a standard optical fiber to a silicon waveguide.

10 2. Description of the Related Art

Planar Lightwave Circuits (PLCs) are intended to transmit and receive signals for short distance data as well as long distance telecommunication systems. For optimal operation, the PLCs must have functional optical components, such as waveguides. These must be small enough in size so that dense integration of devices, including sharp bends in the waveguides, is possible on a single chip.

High-index-contrast material systems, such as a core layer of silicon, on a Silicon On Insulator (SOI) substrate, having a refractive index of ~ 3.5, surrounded by a silica clad with a refractive index of ~ 1.5, offer stronger light confinement in smaller dimensions. One such SOI substrate is shown in figure 1. There could be many practical uses of high-index-contrast waveguide chips, especially in telecommunications, where there is an emphasis on developing ways for routing and processing multi-wavelength optical signals transparently (without converting optical signal to electrical signals and back again). One such example is single mode waveguide based "mux" and "demux" for serializing and separating multi-wavelength optical signals in Dense Wavelength Division Multiplexing (DWDM) application. For this kind of application and others, it is generally desirable to configure the waveguides in single mode propagation to avoid introduction of undesirable effects of differing propagation velocities of different modes.

One of the most difficult challenges facing high-index-contrast optical systems is efficiently coupling light into and out of the chip. Particularly difficult is the coupling of light from a standard optical fiber or external source to a silicon waveguide. A large mismatch between the common optical fiber dimension and that of the high-index-contrast waveguide, and their respective mode sizes, complicates light coupling from one to the other.

A number of techniques have been utilized for optical coupling between waveguides and optical fibers, including prism couplers, grating couplers, tapered fibers and micro-lens

mode transformers. Unfortunately, none of these techniques offer the combination of high coupling efficiency, wavelength independence, reliability, manufacturability, ruggedness, and robustness demanded for use in a low-cost high-volume telecommunications environment.

DESCRIPTION OF THE DRAWINGS

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- FIG. 1 is a schematic of an SOI structure in accordance with the present invention;
- FIG. 2. is a conceptual schematic of a 3-D tapered waveguide in accordance with the present invention;
 - FIG. 3 is a scanning electron microscopic view of a 3D waveguide step; and
 - FIG. 4 is a Profilometer scan showing 9 etched steps of a 3-D waveguide.

DETAILED DESCRIPTION

In order to effectively couple light from optical fibers to high-index-contrast single mode waveguides, there is provided, as an integral waveguide extension, a waveguide section between the waveguide and the fiber that is tapered vertically and also laterally.

In FIG. 2, there is shown a 3-D tapered section that acts as a classic adiabatic modal transformer that transforms the input fundamental mode shape (that is matched to the mode shape of the optical fiber) to that of the waveguide mode making the light coupling more efficient than that with no taper at all. In order to further increase coupling efficiency a special High Numerical Aperture (HNA) fiber may be used as the input fiber. A special splice program is used for coupling a regular SMF28 into our HNA fiber with overall typical loss of 0.2 dB. An intermediate step toward the 3-D taper is the 2-D taper. The 2-D taper is a lateral taper with coupling efficiency lower than that of the 3-D taper, and requires less technological effort.

Turning to FIG. 1, the starting material for fabricating 2-D and 3-D waveguides growing crystalline silicon on insulator (SOI) structures is shown. The insulator is a 2 μ m thick layer of thermally grown SiO₂ on 6" silicon substrates. A 3 μ m thick layer of crystalline silicon is deposited on top of SiO₂ to complete the structure.

Next, as shown in FIG. 2, the mask that initially defines the waveguides on the wafer has various width dimensions starting from 0.5 μ m up to 3 μ m with an increment of 0.25 μ m. At the end of the waveguides, there is included a 2-D flare that extends from the waveguide width to a width of 4 μ m within a horizontal distance of 250 μ m. This taper is necessary to match the mode field diameter (MFD) of the high numerical aperture (HNA) fiber to that of

the waveguide in the horizontal direction. First the 2-D waveguides are defined and etched in the wafer. Subsequent step etches are performed to create a taper along the wafer thickness in the 2-D flare area so that there is also a MFD match between the HNA fiber and the waveguide in the vertical direction.

To define the sub-micron width waveguides, a photolithography technique using AZ P4110 i-line (365 nm) photoresist and a Karl Suss MA6 mask aligner is provided. Next the waveguides are etched using the Oxford silicon dry etching system. C_4F_8 (flow rate 90 sccm) + SF_6 (flow rate 50 sccm) etch chemistry is utilized in the Oxford machine for etching. The measured average depth of the waveguides is ~1 μ m.

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As shown in FIG. 3, a 3-D taper step is then used wherein the entire waveguide is covered with Shipley 1818 positive photoresist. Using an appropriate mask the waveguide is then exposed to UV light leaving only 25 μ m of unexposed areas at the two ends. Dry etching, using the previous chemistry in the Oxford machine is then performed to achieve a 0.167 μ m step. By way of example, FIG. 4 illustrates several more 0.167 μ m deep steps being etched at the two ends of the waveguides to complete the 3-D taper process. The space between each step is 25 μ m. The total etch depth is 1.5 μ m.

The wafer is then diced into appropriate pieces and cleaned. A 2 µm thick SiO₂ top cladding layer is e-beam evaporated to complete the waveguide structure. The two ends of the waveguides are then mechanically polished to a mirror finish. It is possible to measure the coupling and propagation loss in the waveguides without any AR coating deposition. For real coupling loss improvement an AR coating is necessary at the two ends.

An appropriate optical measurement setup that includes a 1550 nm DFB laser, a 24 dBm amplifier, HNA input fiber, a microscope objective and a free space InGaAs detector is used to determine the propagation loss in the waveguides and the coupling loss between HNA fiber and the waveguide. A comparison between at least 3 lengths of waveguide is used to find out the waveguide propagation loss value. Measurements of waveguide loss for 3-D, 2-D and no taper waveguide samples produce the coupling efficiency of each taper.

It is to be noted that theoretical calculations using commercially available software packages (by Photon design, Rsoft) was used to predict coupling loss of 1.8 dB between the HNA fiber and the 3-D waveguides. The actual measurement produced a coupling loss of about 2 dB, very close to the theoretical prediction. For comparison, a 2-D taper is measured to have around 4 dB coupling loss. Without any taper, the coupling loss is larger than 8 dB.

The invention described in the above description is not intended to be limited to the specific form set forth herein, but on the contrary, it is intended to cover such alternatives, modifications, and equivalents as can reasonably be included within the spirit and scope of the appended claims. In particular, the various dimensions and measurements provided above are by way of example only and may be varied as needed. In addition, the present invention also may be used equally as well in non-imaging light concentrators.

CLAIMS

What is claimed is:

5 1. A method for coupling light between a waveguide and an optical fiber, comprising:

providing a waveguide extension located between the waveguide and the optical fiber; and

tapering the waveguide.

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- 2. The method of claim 1, wherein the waveguide extension is tapered vertically.
- 3. The method of claim 1, wherein the waveguide extension is tapered horizontally.

Sheet 1 of 2 SYSTEM AND METHOD OF IMPROVING LIGHT COUPLING EFFICIENCY BETWEEN SILICON WAVEGUIDES AND OPTICAL FIBERS Attorney Docket No.: A5-013 PROV US 630/527-4419

3 μm n (Si) = 3.47 2 μm n (SiO₂) = 1.46 n (Si) = 3.47

FIG. 1

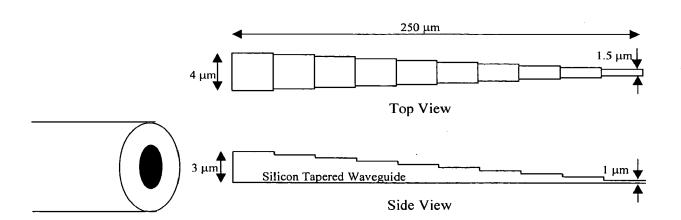


FIG. 2

Sheet 2 of 2 SYSTEM AND METHOD OF IMPROVING LIGHT COUPLING EFFICIENCY BETWEEN SILICON WAVEGUIDES AND OPTICAL FIBERS Attorney Docket No.: A5-013 PROV US

630/527-4419

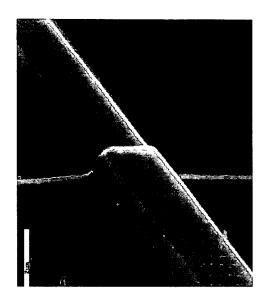


FIG. 3

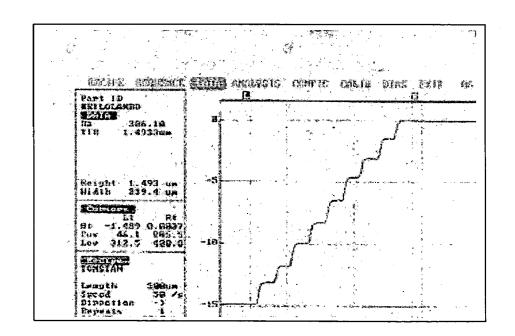


FIG. 4